



**Research and Development Section**  
**Indian Institute of Technology Guwahati**  
**Guwahati-781039, Assam**

Applications are invited for **Walk-in-interview** of the following post(s) for **Contractual recruitment** in the project entitled, "**Indian Nano electronics Users' Programme - Idea to Innovation (INUP-i2i)**" at **Centre for Nanotechnology, IIT Guwahati**.

**Date: 31st July 2024 (Wednesday)**

**Time: 10:00 A.M**

**Venue: Conference Room, Centre for Nanotechnology, IIT Guwahati**

Sl. No.	Project Staff Designation	Number of Vacancies	Pay Recommended (Rs.)	HRA Required (Rs.)	Medical Required (Rs.)	Total Amount (Rs.)	Duration of Appointment in months	Qualifications
1	SRF (DIRECT)	03	35000.00	Yes 6300.00	1250.00	42550.00	03	<p>Post Graduate in basic science or Graduate/Post Graduate in Professional Course selected through a process described through any one of the following:</p> <ol style="list-style-type: none"><li>Scholars selected through National Eligibility Test-CSIR-UGC NET including Lectureship (Assistant Professors hip) and GATE.</li><li>The selection process through National Level Examinations conducted by Central Government Departments and their Agencies and institutions such as DST, DBT, DAE, DOs, DRDO, MHRD, ICAR, ICMR, IISc, IISCR etc.+2yrs of Research Exp.</li></ol> <p><b>Preferable Experience:</b> Expertise in NanoScience, Nanotechnology, Nanobiology, Nanoelectronics and hands-on-experience in Nanofabrication and characterization (such as AFM, SEM, TEM, XRD, Electro-Spinning Device, Materials Printing System, Laser Micromachining, Wire Bonding, Double Sided Mask Aligner,</p>

								Thermal/E-Beam Evaporation, RF Magnetron Sputtering Unit, Oxidation/Diffusion Furnaces, Reactive Ion Etching, FESEM-EBL, Mask Writer, Raman, IR.
2	Project Engineer	01	47000	Rs. 8460.00	Rs. 1250.00	Rs. 56710.00	11	<p>PhD degree Or Master`s degree in Engineering + 3 yrs exp. Or Bachelor`s degree in Engineering + 6 yrs exp.</p> <p><b>Preferable Experience:</b> Expertise in NanoScience, Nanotechnology, Nanobiology, Nanoelectronics and hands-on-experience in Nanofabrication and characterization. Training, Operation and Maintenance of AFM, SEM, TEM, XRD, Electro-Spinning Device, Materials Printing System, Laser Micromachining, Wire Bonding, Double Sided Mask Aligner, Thermal/E-Beam Evaporation, RF Magnetron Sputtering Unit, Oxidation/Diffusion Furnaces, Reactive Ion Etching, FESEM-EBL, Mask Writer, Raman, IR</p>
3	Assistant Project Engineer	01	28500	Rs. 5130.00	Rs. 1250.00	Rs. 34880.00	11	<p>Bachelor`s degree in Engineering</p> <p><b>Preferable Experience:</b> Training, Operation and Maintenance of ODF and Wire Bonder. They will also maintain the Web page for the online applications</p>
4	Associate Project Scientist	01	35000	Rs. 6300.00	Rs. 1250.00	Rs. 42550.00	11	<p>Master`s degree in Science or Bachelor`s degree in Science + 4 yrs exp.</p> <p><b>Preferable Experience:</b> Expertise in Nanoscience, Nanotechnology, Nano biology, Nano electronics and hands-on-experience in Nanofabrication and characterization. Training, Operation and Maintenance of AFM, SEM, TEM, XRD, Electro-Spinning Device, Materials Printing System, Laser Micromachining, Wire Bonding, Double Sided Mask Aligner, Thermal/E-Beam Evaporation, RF Magnetron Sputtering Unit,</p>

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**How to apply and selection process:** Candidates have to appear in the walk-in-interview at 10:00 AM on 31st July 2024 (Wednesday). They have to send advance copy of their CV mentioning all educational qualifications, experience etc. to [nano\\_off@iitg.ac.in](mailto:nano_off@iitg.ac.in) within 29.07.2024 (5PM).

Selection will be based on the performance of the candidate in the interview. Candidates will not be sent any call letter separately.

**For any clarification, contact:** Nano Office, Centre for Nanotechnology, IIT Guwahati

**Email:** nano\_off@iitg.ac.in

**Phone:** 0361 2583066

**NANOSPND EIT00771xDPB008-TSA-4197**

**Assistant Registrar (R&D)**